



Software solutions for  
optimizing micro & nano  
fabrication processes



## Announcement

# BEAMeeting Berlin 2019 at HHI



Date: Wednesday 30st January 2019



Place:

Fraunhofer Institute for Telecommunications, Heinrich Hertz Institute, HHI  
Einsteinufer 37, D-10587 Berlin, rooms 23a & 23b

Time: 09:30 until 16:30

Dear BEAMER user,

Please find below the preliminary agenda. It is still open for inputs and we will be flexible to adjust it to the needs and wishes of the attendees.

We still have some seats available. If you wish to join the meeting and are not yet registered, please do so by e-mail to [assistant@genisys-gmbh.com](mailto:assistant@genisys-gmbh.com) as soon as possible.

Looking forward to seeing you in Berlin soon

The GenISys Team

## BEAMeeting E-Beam Workshop Technical Workshop & Discussion

Date: Wednesday, Jan. 30th, 2019 - Time: 9:30 – 16:30

### Agenda

	Welcome Introduction	9:30 am
Ulrich Hofmann GenISys	GenISys Update	9:50
HHI Ralf Steingrüber	User Presentation	10:20
Daniel Ritter GenISys	FRACTURE module – Exposure optimization (fracturing, field positioning/ordering, exposure order within the field)	10:40
Ulrich Hofmann GenISys	“Bells & Whistles” of PEC Effects on File Size and Pattern Accuracy	11:10
Daniel Ritter GenISys	ProSEM - SEM Metrology Software New feature and Enhancements	11:40
	Lunch	12:00 pm
Stefan Rehbein Helmholtz Zentrum	User Presentation	13:00
Ulrich Hofmann GenISys	TRACER Process Calibration	13:20
Daniel Ritter GenISys	BEAMER Tutorials – algorithmically generated patterns	13:50
Ulrich Hofmann GenISys	Curved Primitive Shapes in BEAMER - Status and Plans	14:10
	Coffee Break	14:40
Olaf Brox Ferdinand Braun	User Presentation	15:00
Daniel Ritter GenISys	BEAMER for Laser Lithography Binary & Grey-Scale	15:20
Ulrich Hofmann GenISys	What's new in BEAMER/TRACER & Roadmap	15:50
	Needs, Wishes & Roadmap Discussion	16:10
	FINAL Closing	16:30

1

Agenda is subject to change